

ABSTRACT

SUBSTRATE TRANSPORT SYSTEM, SUBSTRATE PROCESSING APPARATUS, HAND POSITION ADJUSTMENT METHOD

A substrate transport system includes a hand, a main positioning member permanently mounted on a base, where the main positioning member is engageable with the hand at a position offset by a first distance in the first axis direction and offset by a second distance in the second axis direction from a substrate transfer position, and a control unit that stores a position coordinate in the first axis direction and a position coordinate in the second axis direction of the hand in a state where the hand is positioned by being engaged with the main positioning member.

Figure 7